

35011 U.S. PTO
10/034379



U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10034379	01/03/2002	438	770	2812	D. NHU

**APPLICANTS: Tsurugida Yoshirou;

**CONTINUING DATA VERIFIED:

NO

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 286030/2001 09/20/2001

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PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☒ yes ☐ no
35 USC 119 conditions met ☒ yes ☐ no
Verified and Acknowledged Examiners's initials *or*

ATTORNEY DOCKET NO

OKI.291

TITLE : Method for selectively oxidizing a silicon wafer

U.S. DEPT. OF COMM / PAT. & TM. PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED

3/27/03

ISSUE FEE

Amount Due 1600 Date Paid

☐ TERMINAL
DISCLAIMER

Assistant Examiner

Sanjiv 3/27/03
Primary Examiner

PREPARED FOR ISSUE

CLAIMS ALLOWED

Total Claims ☒ Print Claim for O.G. 1

DRAWING

Sheets Drawn 2 Figs. Drawn 5 Print Fig. 1E

J. Brunson 3/27/03
Application Examiner

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